

EAST Search History**EAST Search History (Prior Art)**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L26	23	L24 not L25	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 14:05
L25	5	(US-20030078738-\$ or US-20040078319-\$ or US-20040102934-\$ or US-20050016947-\$). did. or (US-5719796-\$ or US-6571371-\$ or US- 6615097-\$ or US- 6628809-\$ or US- 6643616-\$ or US- 6728591-\$ or US- 6757645-\$ or US- 6763277-\$ or US- 6774998-\$ or US- 6802045-\$ or US- 6812045-\$ or US- 6905895-\$).did. or (US- 5866437-\$ or WO- 200177979-\$ or WO- 200277589-\$ or US- 20030135302-\$ or US- 20040078319-\$ or US- 20050010319-\$).did.	US-PGPUB; USPAT; DERWENT	OR	OFF	2010/12/15 14:05
L24	28	(US-20040078319-\$ or US-20050016947-\$ or US-20030078738-\$ or US-20040102934-\$ or US-20030101251-\$ or US-20050010319-\$). did. or (US-6774998-\$ or US-6615097-\$ or US- 5719796-\$ or US- 6757645-\$ or US- 6643616-\$ or US- 6802045-\$ or US- 6763277-\$ or US- 6571371-\$ or US- 7107571-\$ or US- 6728591-\$ or US- 6812045-\$ or US-	US-PGPUB; USPAT; DERWENT	OR	ON	2010/12/15 14:05

		6628809-\$ or US- 6905895-\$ or US- 6198980-\$ or US- 6263255-\$ or US- 7333871-\$ or US- 6810296-\$ or US- 5583780-\$).did. or (US- 5866437-\$ or US- 20040078319-\$ or WO- 200277589-\$ or US- 20050010319-\$ or WO- 200177979-\$ or US- 20030135302-\$).did.				
L19	1	"5583780".pn.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 12:18
L18	18	("20020051567" "20020082738" "20020088952" "20020192966" "20030097198" "3614640" "4578648" "5396433" "5482881" "5810928" "5838445" "6020264" "6409576" "6486492" "6594598" "6638778"). PN. OR ("6810296"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 12:04
L17	822	(furnace etch CVD (chemical adj Vapor adj deposition)) near2 model\$4 and semiconductor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:55
L16	71	((ANDREJ) near2 (MITROVIC)).INV.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:49
L15	107	((ERIC) near2 (STRANG)).INV.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:49
L14	38	(geometric physical dimension) with semiconductor with (equipment device tool) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:41
L13	12	("20020133801" "5590063" "6530069" "6581029").PN. OR ("6802045").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2010/12/15 11:39

L12	73	(geometric physical dimension) with (equipment furnace CVD (chemical adj Vapor adj deposition)) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:36
L11	4	L7 and (geometric physical dimension) with (equipment furnace CVD (chemical adj Vapor adj deposition)) adj (model \$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:35
L10	124	L7 and (geometric physical dimension) with (equipment furnace CVD (chemical Vapor deposition)) adj (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:34
L9	120	L7 and (geometric physical dimension) with (furnace CVD (chemical Vapor deposition)) adj (model \$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:33
L8	1424	L7 and (geometric physical dimension) with (model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:32
L7	6990	L3 OR L4 and (semiconductor adj tool near3 model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:32
L6	6993	L3 OR L4 and (semiconductor adj tool)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31
L5	7259	L3 OR L4 and (semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31

L4	1367	furnace near2 model\$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:31
L3	6990	(CVD (chemical Vapor deposition)) near2 model\$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/15 11:30
S99	19	US-6571371-\$ DID OR US-6763277-\$ DID OR US-6529789-\$ DID OR US-6628809-\$ DID OR US-6728591-\$ DID OR US-6774998-\$ DID OR US-20050010319-\$. DID. OR US- 20040044513-\$ DID. OR US-6615097-\$ DID. OR US-6618856-\$ DID. OR US-5539652-\$ DID. OR US-6581029-\$ DID. OR US-20030003607-\$. DID. OR US-5377116-\$. DID. OR US-5629877-\$. DID. OR US-6625497-\$. DID. OR US-6185472-\$. DID. OR US-7047095-\$. DID. OR US-6587744-\$. DID.	US-PGPUB; USPAT	OR	ON	2010/12/14 15:02
S98	0	(spatially adj resolved) with ((furnace CVD) near2 model\$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:39
S97	9	((spatially adj resolved) near3 model\$4) and (semiconductor) with tool	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:37
S96	139	(spatially adj resolved) and (semiconductor) with tool	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36

S95	1556	(spatially adj resolved) and (semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36
S94	4333	(spatially adj resolved)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:36
S93	2	"6263255".pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/12/14 13:32

EAST Search History (Interference)

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12/15/2010 2:06:46 PM**C:\ Documents and Settings\asaxena\My Documents\EAST\Workspaces\10673138.wsp**